

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Bernas et al.

Serial No.: 10/001,346

Filed: October 31, 2001

For: SOLID FREEFORM FABRICATION OF
LIGHTWEIGHT LITHOGRAPHY STAGE



GAU: TBA

Examiner: TBA

Assistant Commissioner for Patents
Washington, DC 20231

**INFORMATION DISCLOSURE STATEMENT
UNDER 37 CFR § 1.97 - 1.98**

Pursuant to 37 CFR 1.98, in addition to the references cited in the above-referenced patent application, the Applicants hereby disclose to the United States Patent and Trademark Office the references recorded on the enclosed PTO Form 1449.

Date: 11/15/02

Date of Deposit: 11/15/02

I hereby certify that this paper (along with any paper referred to as being attached or enclosed) is being deposited with the United States Postal Service on the date indicated above with sufficient postage as first class mail in an envelope addressed to the Commissioner of Patents and Trademarks Washington, DC 20231

Signature: [Signature]

Respectfully submitted,

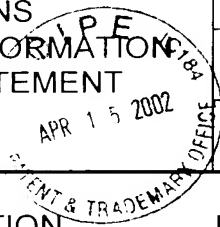
[Signature]

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LIST OF PATENTS AND
PUBLICATIONS
FOR APPLICANTS INFORMATION
DISCLOSURE STATEMENT

APPLICANT Bernas et al.

FILING DATE 10/31/01

GROUP TO
BE ASSIGNED TBA

REFERENCE DESIGNATION

U.S. PATENT DOCUMENTS

Examiner Initial		Document Number	Date	Name	Class	Sub-Class	Filing Date if Approp.
	AA	2001/0028462	10/11/01	Ichihara et al.			
	AB	5,204,055	4/20/93	Sachs et al.			
	AC	5,387,380	2/7/95	Cima et al.			
	AD	5,479,257	12/26/95	Hashimoto			
	AE	5,530,257	6/25/96	Mizutani et al.			
	AF	5,623,853	4/29/97	Novak et al.			
	AG	5,699,621	12/23/97	Trumper et al.			
	AH	5,807,437	9/15/98	Sachs et al.			
	AI	5,999,254	12/7/99	Seibert et al.			
	AJ	6,036,777	3/14/00	Sachs			
	AK	6,188,150	2/13/01	Spence			

FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Sub-Class	Translation Yes	No
	AL							
	AM							
	AN							
	AO							
	AP							
	AQ							

OTHER ART (Including Author, Title, Date, Pertinent Pages, etc.)

	AR		"Extreme Ultraviolet Lithography," Gwyn, C., et al., EUV LLC, Nov. 1999, pps. 97-141.
	AS		"Three Dimensional Printing," website: http://web.mit.edu/tdp/www/applications.html
	AT		

EXAMINER:

DATE CONSIDERED:

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609: draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Information Disclosure Statement-PTO-1449 (Modified)